

13th SPIE conference: “Videometrics, Range Imaging and Applications”

25-26 May 2011, Munich, Germany

From May 25th to 26th 2011, the 13th SPIE conference “Videometrics, Range Imaging and Applications” was held at the International Conference Centre in Munich, Germany. The conference was organized as part of SPIE Optical Metrology conference that included three other meetings (Optical Measurement System for Industrial Inspection, Modeling Aspects in Optical Metrology and O3A – Optics for Arts, Architecture, and Archeology). The conference chairs were Fabio Remondino (FBK Trento, Italy) and Mark Shortis (RMIT University Melbourne, Australia). The conference was co-located with Laser World of Photonics 2011, sponsored by SPIE, WLT German Scientific Laser Society and EOS European Optical Society.

The first Industrial Vision Metrology conference was arranged by Sabry El-Hakim (Carleton Univ., Canada) in 1991 and held at Winnipeg in Canada. Renamed to Videometrics, it was then part of Photonics East at Boston and Philadelphia (1992-1995). The conference was then moved to southern California in 1997, first as part of SPIE Photonics West and later in SPIE Electronic Imaging. The last meeting was held in San Diego in 2009 as part of SPIE Optics + Photonics.

The 2011 Videometrics meeting featured 38 papers - 22 from Europe, 12 from Asia, 2 from USA/Canada and 2 from New Zealand. The conference was divided into 6 technical sessions, with 27 papers delivered as oral presentations and 9 papers presented in the poster session. The topics of the oral sessions were "Accuracy and Performance Evaluation", "Image- and range-based modelling", "Accuracy, system performance and orientation analysis", "3D Applications", "3D modeling and Motion Capture" and "Calibration and orientation algorithms".

There were two invited presenters, Thomas Luhmann (Jade University, Germany) who gave a keynote titled “3D imaging: how to achieve the highest accuracy” and by Werner Boesemann (AICON 3D systems GmbH, Germany) with a keynote on “Industrial Photogrammetry: challenges and opportunities”.

The whole SPIE Optical Metrology 2011 conference brought together scientists, engineers, researchers, and product developers engaged in optical metrology, art conservation and multimedia. The Munich event was an important exchange of ideas and views among the attendees (more than 300 for the cluster of four Optical Metrology conferences). The single stream of Videometrics sessions attracted an increasing worldwide interest, with up to 70 participants in the audience for each of the invited presentations.

Fabio Menna – 3D Optical Metrology, FBK Trento, Italy